



Our Docket No: 42P10058

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Han-Ming Wu et al.

Serial No: 09/752,938

Filed: December 29, 2000

For: Purging Gas from a
Photolithography Enclosure
Between a Mask Protective
Device and a Pattern Mask

Examiner: Nguyen, Hung

Art Unit: 2851

PRELIMINARY AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to examination of the present application, please enter the following amendments and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

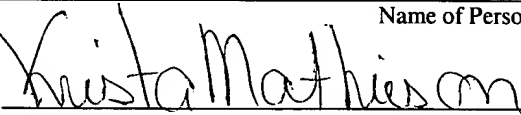
I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

September 23, 2003

Date of Deposit

Krista Mathieson

Name of Person Mailing Correspondence



Signature

September 23, 2003

Date